

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re New Patent Application of)
Hidekazu MIYAIRI et al.)
Japanese Priority Application Nos.)
2002-268222 & 2002-274220) Attn: Applications
Filed: 09/13/2002 & 09/20/2002) Branch
For: LASER APPARATUS, LASER)
IRRADIATION METHOD, AND)
MANUFACTURING METHOD OF)
SEMICONDUCTOR DEVICE) Date: September 10, 2003

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

Please preliminarily amend the subject application as follows: